## **EAST Search History**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	63945	(electrode anode cathode) same pad and contact and (wafer semiconductor microelectronics micropiece) and abrasive and (proximate proximity) without near3 (touching contacting)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:13
L2	6	1 and 205/147	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:09
L3	6	1 and 205/147.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:11
L4 ·	41	1 and 204/242	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:12
L5	48271	(electrode anode cathode) same pad and contact and (wafer semiconductor microelectronics micropiece) and abrasive and (proximate proximity) without near (touching contacting)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:14
L6	26	5 and (204/242.ccls. or 205/147. ccls.)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:15
L7	1	("6398625").PN.	USPAT; USOCR	OR	OFF	2007/07/03 07:18
L8	1	("6168693").PN.	USPAT; USOCR	OR	OFF	2007/07/03 07:19
L9	.1	("6103096").PN.	USPAT; USOCR	OR	OFF	2007/07/03 07:19
L10	1	("6797132").PN.	USPAT; USOCR	OR	OFF	2007/07/03 07:22
L11	98	(205/147).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT	OR	OFF	2007/07/03 07:22

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## **EAST Search History**

L12	1394	(204/242).CCLS.	US-PGPUB; USPAT; USOCR;	OR	OFF	2007/07/03 07:22
			EPO; JPO; DERWENT			,

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